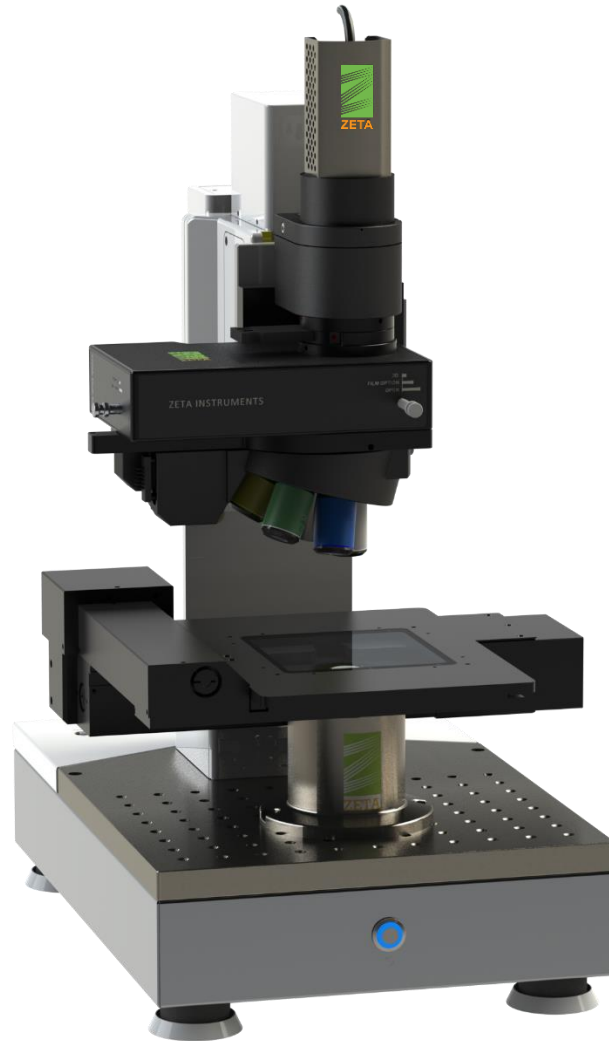


Zeta3D OPTICAL PROFILER

Zeta-20



IMAGING THE IMPOSSIBLE

TRUE COLOR 3D • DIC • BRIGHT FIELD • DARK FIELD • POLARIZED LIGHT
IMAGE • THROUGH TRANSMISSIVE IMAGE • WHITE OR BLUE LED LIGHT
SOURCE • THIN FILM THICKNESS • DIAMOND SCRIBE • HDR IMAGING •
MULTI-SURFACE IMAGING • AUTO FOCUS • AUTO SEQUENCE •
AUTOMATED DEFECT INSPECTION • WIDE AREA STITCHING

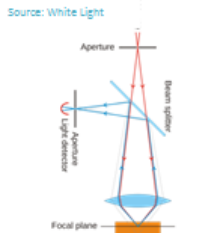
TECHNOLOGY TOOLKIT

Developed in 2007, the revolutionary **Confocal Grid Structured Illumination (CGSI)** is the powerful technology in all Zeta Optical Profilers... but in a Zeta, it's called a **ZDot™**.

Evolution of Confocal Optical profiling technology

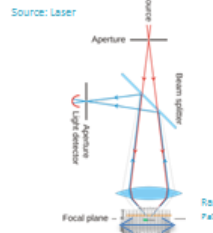
1957

Principle of Confocal Microscopy
Marvin Minsky



1978

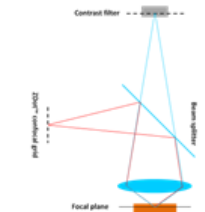
Laser Scanning Process
Thomas and Christophe Cremer



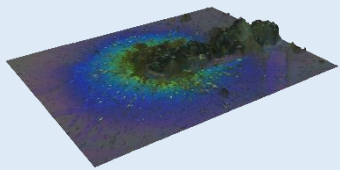
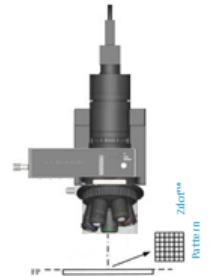
2007.....

Confocal Grid Structured Illumination (CGSI)
James Xu and Ken Lee

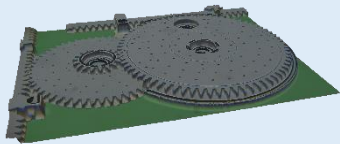
Source: High Brightness, Long-life, Full Spectrum LEDs



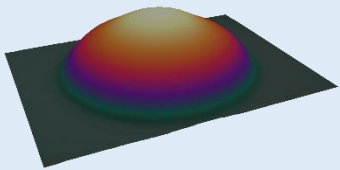
Today



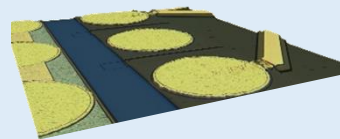
Laser Ablation on Si with Film



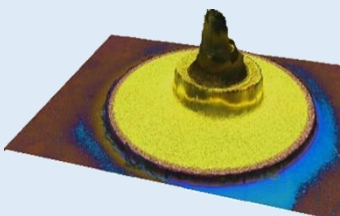
MEMS Device



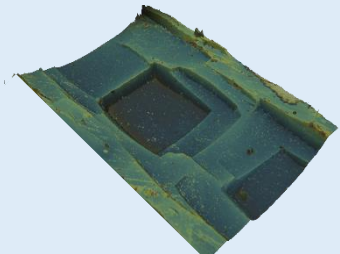
Micro Lens



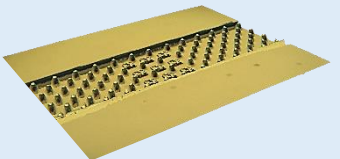
IC Structure



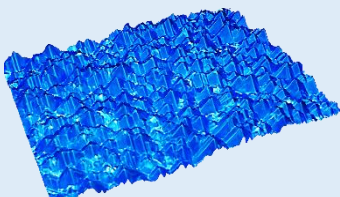
Gold Bump on IC



Crystalline Si for Solar Cells

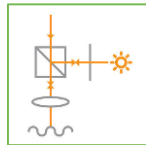


Microfluidic Structure



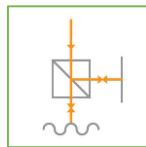
Nitride coated Si Pyramids

Zeta pioneered the science of multi-mode metrology, packing five powerful techniques into one compact optical package.



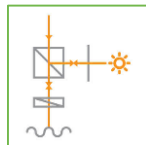
ZDot

Zeta's proprietary 3D imaging technology combines innovative optics with powerful software algorithms to produce great results on a variety of surfaces



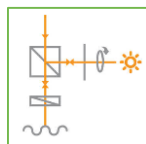
ZX5 & ZX100

Vertical Scanning Interferometer optics enables wide area measurements with a high Z resolution



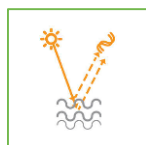
ZIC

Zeta's unique interference contrast technique providing enhanced & quantitative images of sub-nanometer level roughness



ZSI

Convert any standard objective into a shearing interferometer to provide very high Z resolution images



ZFT

Integrated broad-band reflectometer for thin film thickness and surface reflectance measurements

HARDWARE OPTIONS

Imaging Options

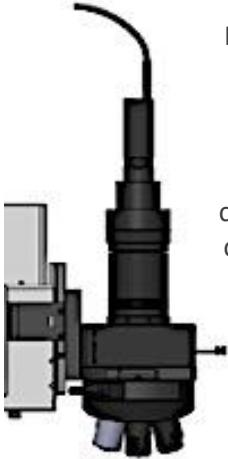


Image parameters such as field of view (FOV) and lateral resolution are determined by the combination of camera, coupler and objective choices. A variety of color and black & white cameras, designed specially for the Zeta system, are available; a popular option for research labs is the 2.8 MPix software programmable multi-resolution color CCD camera. Combined with an extensive suite of objectives and coupling lenses, the flexibility of configuring the Zeta optics means that the same tool can be used to image a FOV as small as $45 \times 35 \mu\text{m}$ all the way up to $9.5 \times 7.5 \text{ mm}$. Broadband white light or 405nm monochromatic high brightness LED light sources are available. Surfaces can be imaged in bright field, dark field or differential image contrast modes. ZDot™ technology eliminates the need for expensive objectives by using standard objectives.

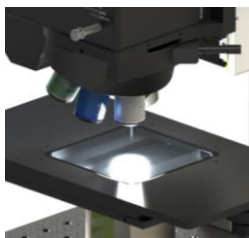


Comprehensive Set of Objectives:

Standard, Long, Ultra-long, Immersion and Refractive Index Corrected

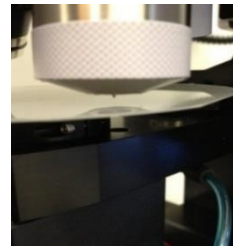
Stage and Sample Handling Options

The Zeta-20 can be equipped with a manual or a motorized XY stage. It can be configured to accept samples as large as 14-inches x 7-inches. Specialty stages include tip-tilt stages (course and fine adjustment) and motorized piezo Theta 360 degree stages. Chucks options include manual rotary, tilt, vacuum chucks, square and circular glass options for transmitted illumination (backlight for transparent substrates), and special apparatus for wire, magnetic and solar applications.



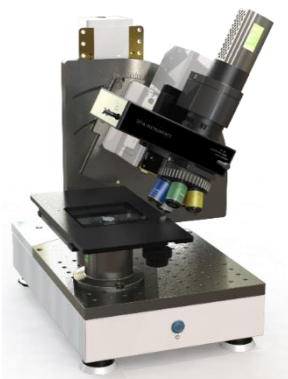
Transmitted Illumination: High brightness LEDs are used to illuminate transparent samples for through transmissive imaging.

Diamond-Scribe: Precision diamond tipped scribe to mark features of interest for further analysis on AFM, SEM or other tools.

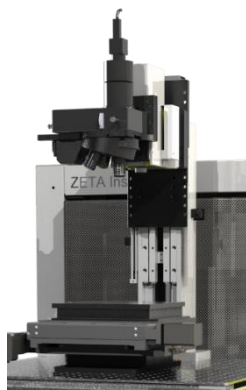


Advanced Hardware Options

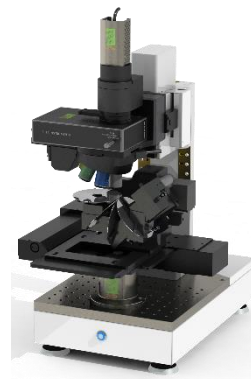
The Zeta Optical Profilers can be easily upgrade to meet your measurement requirements. Shown below are some application specific hardware configurations.



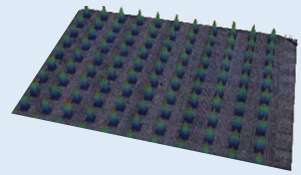
Swivel Head



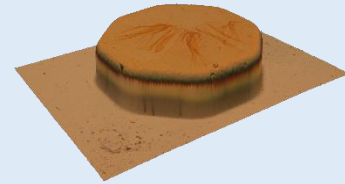
280mm Extended Z Range



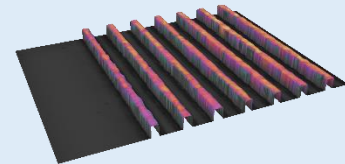
Chamfer / Edge Inspection



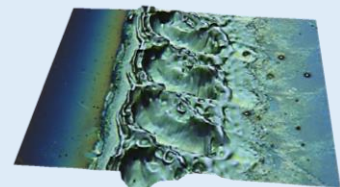
Microneedles for Drug Delivery



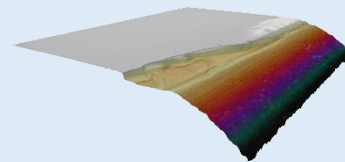
Bump for WLCSP



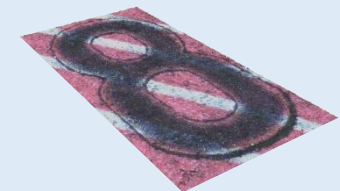
2µm RDL for FOWLP



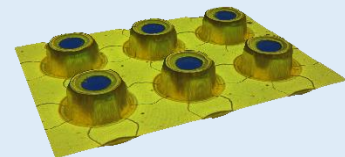
Laser ablated thin film surface



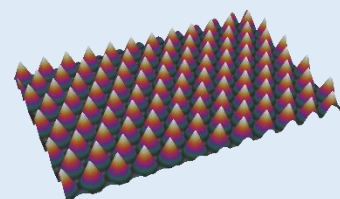
SiC Wafer Edge Defect Profile



Feature on Currency Note



VCSEL Device



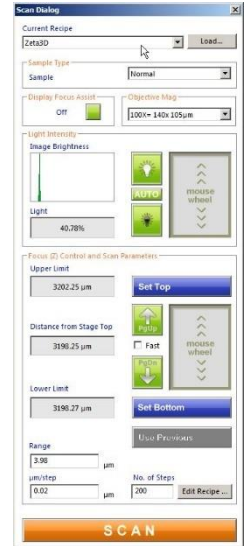
PSS – Patterned Sapphire

SOFTWARE OPTIONS

Fastest Time to Usable Data

Preparing samples and equipment for data acquisition should be **fast**. The ease of use and automation features of a Zeta3D™ enables the user sees the fastest 'time to usable data'. Image Acquisition Options include:

- Automatic illumination control
- Auto-focus
- Software selectable field of view
- Auto-sequence for multiple sites
- Time delay acquisition
- Multiple-layered acquisition (up to 8 layers)
- Wide area stitching
- Pattern recognition for automatic detection and scanning
- High dynamic range (HDR) for surfaces with high contrast variation
- User manager with password protected recipe access

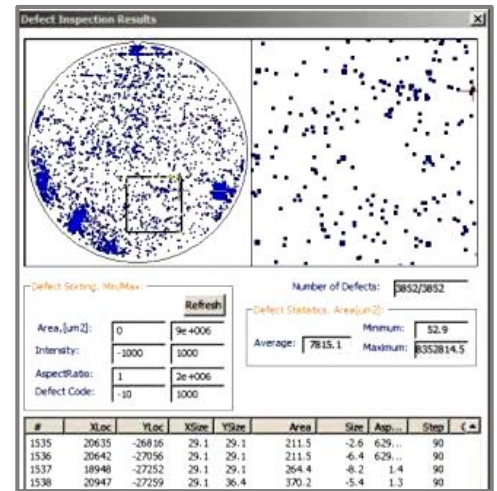


Simple Scan Setup

Image Analysis Software Included, with Options

Zeta3D comes with a comprehensive software package, offering a complete suite of analysis functions and recipes. Some of the highlights are:

- Roughness analysis based on ISO standards
- 2D and 3D roughness
- 2D and 3D step height analysis
- Single & multiple cross section analysis
- Automatic feature detection
- CD measurement of detected features
- Bow and shape measurement
- Automated defect inspection (optional)
- Texture analysis (optional)
- Contact line analysis
- Film Spectrometry (optional)

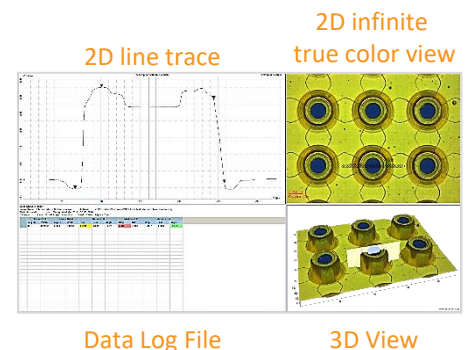


Automatic Optical Inspection (AOI)

Communicating Results

Advanced functionality allows for easy reporting – from exporting data to run in your favorite image processor, or simply taking a screenshot to drop into a presentation. Advanced Options include:

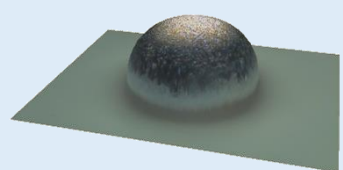
- Custom report format
- Offline Analysis License
- Additional analysis package – ZMorf
- Compatibility with 3rd party packages
 - MATLAB, SPIP



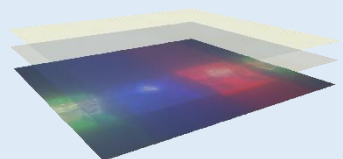
Simple and Effective Analysis Report



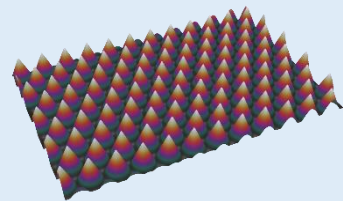
Firing Pin mark on a casing



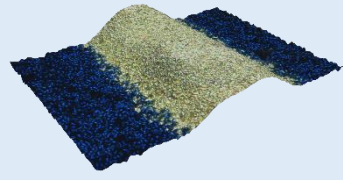
FOWLP Bump over Passivation



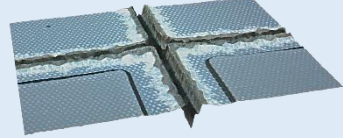
RGB pixels inside a smart phone



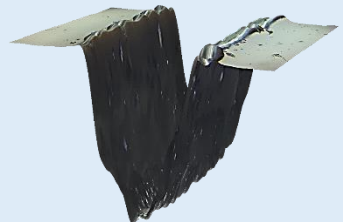
Patterned Sapphire Substrate



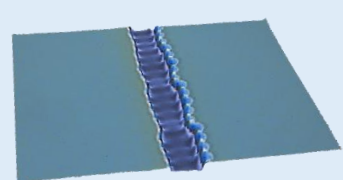
Contact line on a solar cell



Laser dicing on a LED wafer



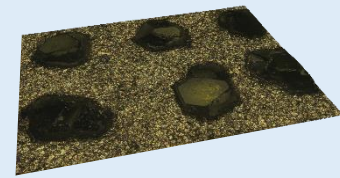
Deep trench in PDMS



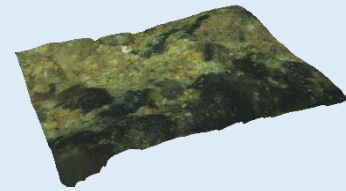
Isolation trench on solar cell

APPLICATIONS SOLUTIONS

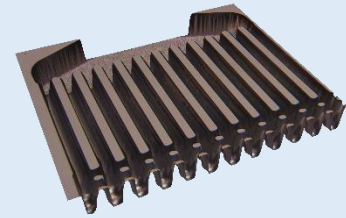
Zeta Instruments creates turn-key metrology solutions for a variety of applications. We combine multi-mode optics, advanced electronics and data analysis algorithms to create 'one-button' production ready packages.



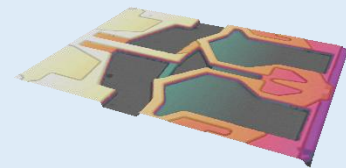
CMP Pad Conditioner



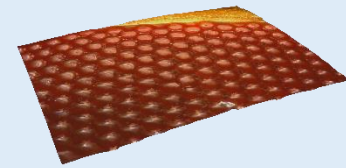
Asphalt Surface



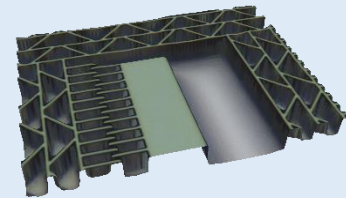
Microfluidic flow separator



Read/Write Head



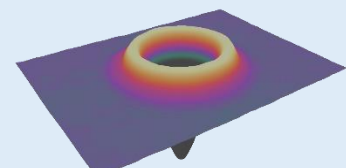
Eye of a Fly



MEMS Device



Diamond Wire for Si wire saw

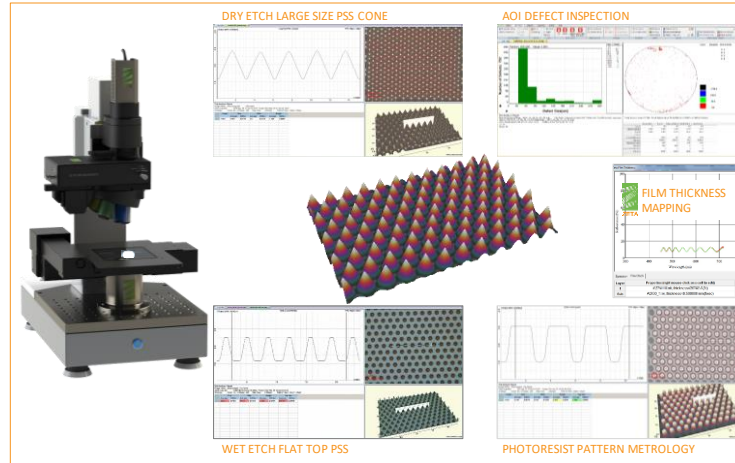


Soft Laser Mark

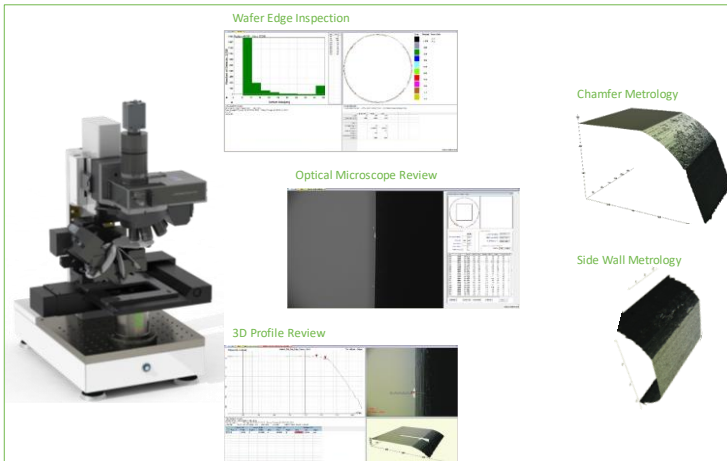
High Brightness LED (PSS)

Application Suite:

- Film Thickness
- CD Measurements
- Dry Etch PSS Height
- Wet Etch PSS Height
- Defect Inspection
- Defect Review
- 3D Imaging of Defects



Extreme OD (XOD)



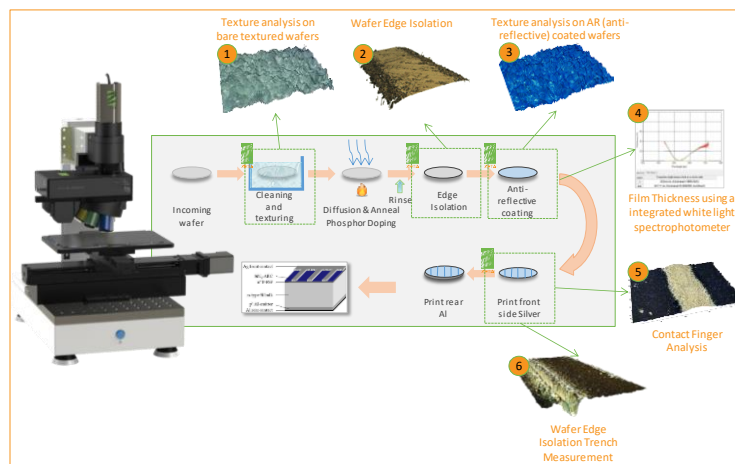
Application Suite:

- Wafer Chamfer Shape
- Wafer Chamfer Roughness
- Side Wall Shape
- Top Edge Defect Mapping
- Side Wall Defect Mapping
- Defect Review
- 3D Imaging of Defects
- Diamond Scribe Marking

PV Solar Cell

Application Suite:

- Bare Wafer Texture
- Edge Inspection
- Nitride Wafer Texture
- Film Thickness
- Contact Line Height
- Edge Trench Depth



Wafer Edge Isolation Trench Measurement

Zeta-20 Optical Profiler

PERFORMANCE

Z Resolution	0.1nm ¹
Z Repeatability (Step Height)	< 0.5% ²
Z Accuracy (Step Height)	< 0.75% ³
RMS Repeatability (Roughness)	0.05nm ⁴

OPTICS & ILLUMINATION

Multi-Mode Measurement & Imaging Capability	ZDot (Confocal Grid Structured Illumination), True Color, Standard ZFT (Thin Film Spectrometer), Option ZIC (Interference Contrast Imaging), Option ZX5/100 (Vertical Scanning Interferometer), Option ZSI (Shearing Interferometer), Option
Illumination Optics	Triple optical path for Multi-Mode Optics Dual Ultra Bright LED, White, Standard Dual Ultra Bright LED, Blue, Option
Illumination Options	Bright Field, Standard Polarized Light, Option Through Transmissive (Bottom), Option Dark Field, Option Multiple Angle Side Illumination, Option

OBJECTIVES & IMAGING

Objective Options	1.25X - 150X Normal Objectives Long Working Distance Objectives, Ultra Long Working Distance Objectives Through Transmissive Objectives, Liquid Immersion Objectives Vertical Scanning Interferometry Objectives
Field of View	From 9µm x 7µm up to 18mm x 14mm (objective dependent)
Turret Options	From 1-position up to 6-position Manual 6-position Automated
Camera	Color CCD camera, Software controlled, Variable image size: From 640x480 pixels up to 1920x1440 pixels (larger pixel formats also available for custom applications)
Total Magnification	5500 times optical / 66000 times digital

SCAN RANGE & SPEED

Z Scan Range	Up to 25mm in a single scan
Z Scan Speed	> 150µm/sec

STAGE AND SAMPLE DIMENSIONS

Z Scan Stage	40mm Standard, Closed loop with optical feedback control, 13nm resolution 240mm Extended Option, Closed loop with optical feedback control, 13 nm resolution 200µm Ultra High Precision Piezo Stage Option, 0.1nm resolution
XY Stage Options	Manual XY Stage: Up to 175mm x 350mm Motorized XY Stage: Up to 180mm x 200mm
Tip/Tilt Options	Precision & Coarse Tip/Tilt stage options up to 20° of tilt "CM" Option for disk and wafer edge measurements "Swivel Head" Option for tilting optical head around large samples
Sample Chuck	360° rotary chuck with vacuum connection Glass chuck for through transmissive imaging (backlight) Custom chucks and fixtures for specific applications
Sample Weight	Up to 15Kg, depending on XY stage selected >15Kg Option available for specific applications
Sample Size	XY Size : Up to 350mm depending on XY Stage Z Size: 125mm, Standard; 350mm with Extended Z-Stage Option (Custom extended staging options available)

SOFTWARE FEATURE SET

Zeta3D	The comprehensive Zeta3D software package is a fully integrated data acquisition, analysis and reporting package. Step height, roughness, profile and area analysis based on ISO standards are all included in the Zeta3D software package.
Advanced Applications	CD - Critical Dimension, Feature detection, Multi-surface, Film thickness, HDR - high dynamic range, Bow/Warp Mapping, Wafer Edge Profile, AOI - Defect Inspection
External Applications & Controls	ZMorf, MATLAB, SPIP, TCP/IP, SECS/GEM
Automation Suite	Auto-illumination, Autofocus, Auto sequence, Auto deskew, Pattern recognition, Auto-stitching

CALIBRATION

Zeta Calibration Reference	Includes 4 reference step heights for Z Calibration: Nominal 8, 25, 50 and 100 µm Varying Pitch patterns for XY Calibration and Patterns for Optical Resolution Testing
Zeta Film Reference	270nm oxide film standard
NIST Traceable Standards	Application specific Step Height and Film Thickness standards

DATA ACQUISITION AND DISPLAY

PC	64-bit Windows 7 Multi-core Intel i7 16GB RAM / 1 TB HDD 3D Accelerator Card with 250MB VRAM
Display	24-inch LCD, Standard / 30-inch LCD, Option

VIBRATION ISOLATION

Vibration Isolation	Vibration dampening feet included with system Optional active vibration isolation modules available for high noise environments
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WARRANTY

Comprehensive warranty	1 year comprehensive warranty
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Zeta3D TECHNICAL SPECIFICATIONS

Capabilities of Zeta3D™ systems will depend on the configuration purchased

